



10-15-04

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. ....10/664,744  
Filing Date .....September 18, 2003  
Inventor.....Michael T. Andreas  
Assignee .....Micron Technology, Inc.  
Group Art Unit ..... 2823  
Examiner .....Fernando L. Toledo  
Attorney's Docket No. .... MI22-2711  
Title .... Method of Polishing a Semiconductor Substrate, Post-CMP Cleaning  
Process, and Method of Cleaning Residue from Registration Alignment  
Markings (As Amended)

**RESPONSE TO SEPTEMBER 23, 2004 OFFICE ACTION**

To: Mail Stop Amendment  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**VIA EXPRESS MAIL**

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)  
Wells St. John P.S.  
601 West First Avenue, Suite 1300  
Spokane, WA 99201-3828

Responsive to the Office Action dated September 23, 2004, Applicant  
amends and remarks as follows:

**AMENDMENTS**

**In the Title**

Please replace the title with:

--Method of Polishing a Semiconductor Substrate, Post-CMP Cleaning Process, and Method of Cleaning Residue from Registration Alignment Markings--.